

## **SPECIFICATION**

- o Amend the Abstract beginning at page 14, line 4, as follows:

A MEMS device having a movable mirror pixel supported on a substrate and coupled to a motion actuator ~~located between the mirror pixel and the substrate~~ so as to enable rotation of the mirror pixel about an axis lying within the mirror plane. In one embodiment ~~of the invention~~, the motion actuator has a movable electrode, on which the mirror pixel is mounted. The movable electrode is supported on the substrate by a pair of upright springs, each having two parallel segments joined at one end ~~of the spring~~ and disjoint at the other end. One disjoint segment end is coupled to the substrate, while the other disjoint segment end is coupled to the movable electrode. The end of the upright spring corresponding to the joined segment ends points away from the substrate such that (i) the spring body protrudes through a narrow slot in the mirror pixel and (ii) the mirror plane lies at about the mid-point of the spring. ~~Advantageously, a mirror pixel of the invention enables implementation of a segmented mirror with tightly spaced mirror pixels providing a fill factor higher than about 98%.~~